IN THE CLAIMS:

Please CANCEL claims 1-15 without prejudice to or disclaimer of the recited subject matter.

Please ADD new claims 16-25, as follows. For the Examiner's convenience, all claims currently presented are reproduced below.

1-15. (Canceled)

16. (New) A movable stage apparatus comprising a reticle stage on which a reflecting reticle is to be mounted, wherein when a space is divided by a plane including a reflection surface of the reticle, a guide surface to guide movement of the master reticle stage is arranged in a space opposite to a space where an exposure light beam to be reflected by the reticle passes,

wherein said reticle stage comprises a coarse movement stage which reciprocally moves on the guide surface formed on a base of the movable stage apparatus in a scanning direction along said guide surface in non-contact with said coarse movement stage and having a six-axis alignment mechanism,

wherein the reflection surface of the reticle is arranged to face vertically downward, and said fine movement stage is supported in non-contact with said coarse movement stage and is positioned in six-axis directions by a six-axis alignment mechanism which can perform position control of said coarse movement stage in six-axis alignments, and by a self weight support mechanism which supports a weight of said fine movement stage, and

wherein said six-axis alignment mechanism does not perform position control of said fine movement stage, said fine movement stage is urged against said coarse movement stage

by the magnetic force, and abuts against an alignment section arranged on said coarse movement stage, so that a position and a posture of said fine movement stage are regulated.

17. (New) The apparatus according to claim 16, wherein said reticle stage is movably supported in non-contact with a base of the movable stage apparatus.

18. (New) The apparatus according to claim 16, wherein a driving point of said coarse movement stage is arranged between the reflection surface of the reticle and said guide surface.

19. (New) The apparatus according to claim 16, wherein a thrust generating mechanism for said coarse movement stage includes a plurality of linear motors arranged parallel to the scanning direction, and said linear motors are controlled independently of each other, so that a rotational posture of said coarse movement stage is controlled.

20. (New) The apparatus according to claim 19, wherein stators of said linear motors are movably supported in non-contact with said base, and comprise counter masses which move in a direction opposite to a driving direction of said coarse movement stage due to a moving reaction force of said coarse movement stage.

21. (New) The apparatus according to claim 19, wherein driving points for said linear motors and barycentric positions of said stators substantially coincide with each other at least in the non-scanning direction and the gravity direction.

22. (New) The apparatus according to claim 16, further comprising an electromagnet which transmits a force, generated upon acceleration or deceleration of said coarse movement stage, to said fine movement stage in non-contact with said fine movement stage.

23. (New) The apparatus according to claim 16, wherein said self weight support mechanism so supports a weight of said fine movement stage so as to push up said fine movement stage toward said coarse movement stage with a magnetic force.

24. (New) The apparatus according to claim 16, wherein said alignment section causes three spherical bodies to engage with a circular conical groove, a V-groove, and a flat surface, respectively, thus performing alignment.

25. (New) The apparatus according to claim 16, wherein an interferometer to measure rolling, pitching, and a Z-axis position as a vertical direction of said fine movement stage, an interferometer to measure yawing and a Y-axis position perpendicular to the vertical direction, and an interferometer to measure an X-axis position perpendicular to Y and Z axes are mounted on a top plate of said fine movement stage, and a long mirror to measure the Z-axis position, rolling, and pitching, a short mirror to measure the Y-axis position and yawing, and a long mirror to measure the X-axis position are mounted on a base which supports a projection optical system and which is vibration-insulated from a base that supports said reticle stage.